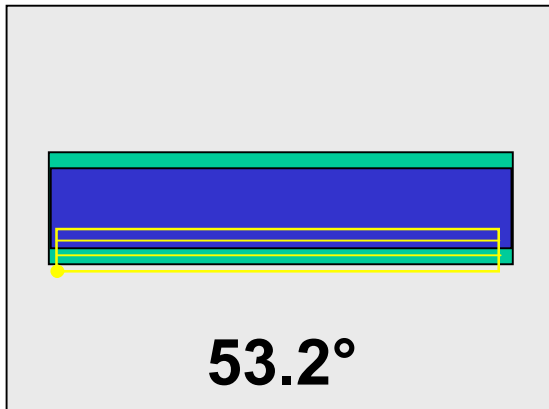
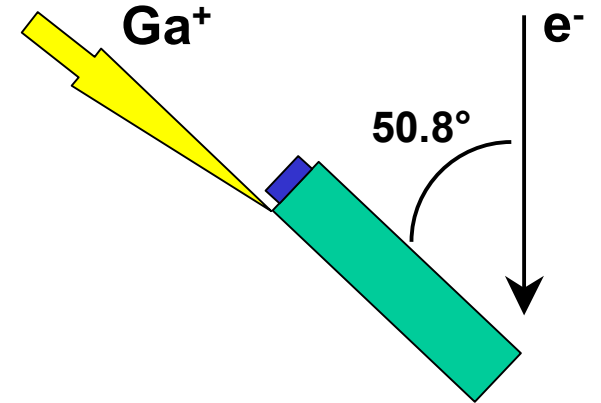
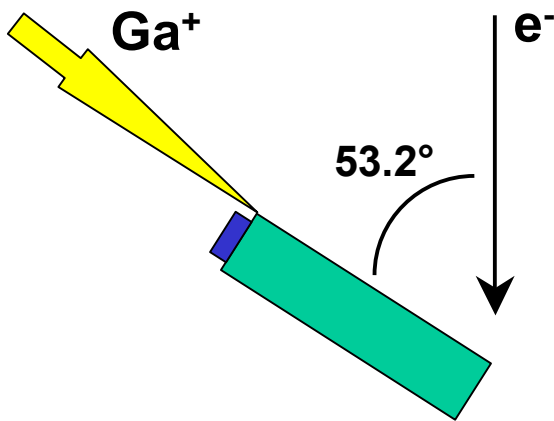
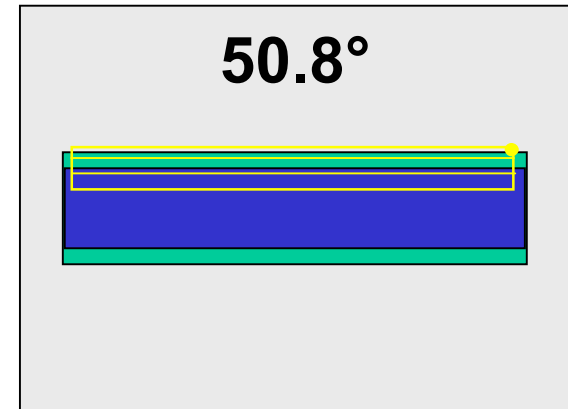


Mnemonic for Side/Tilt Angle Setting Sample for Final FIB Polishing in FEI Dual Beam

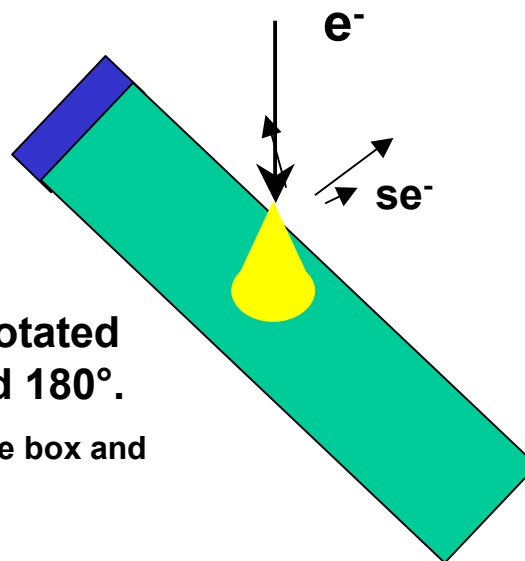
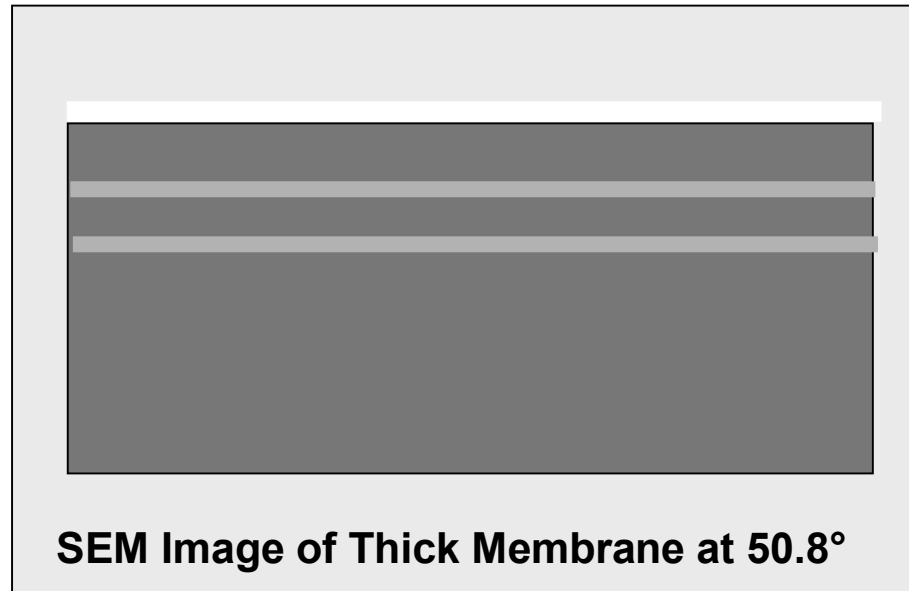
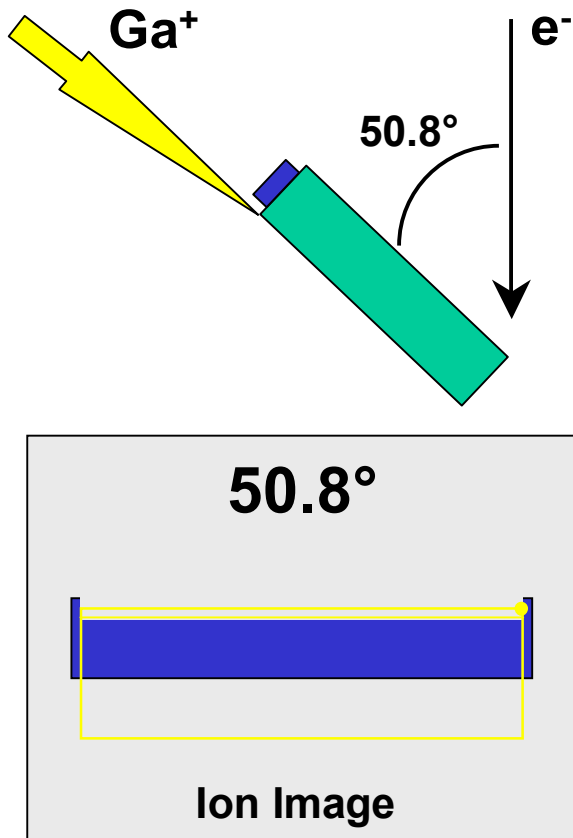


The bottom of the image is closest to the electron beam, i.e. physically towards top.



Note: The ion beam convergence half angle is not 1.2°!

Endpoint Determination for TEM Samples in a Dual Beam Instrument

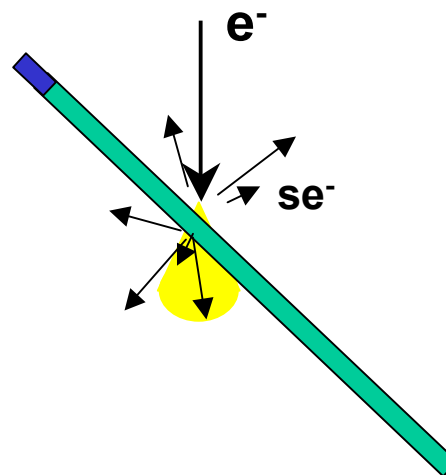
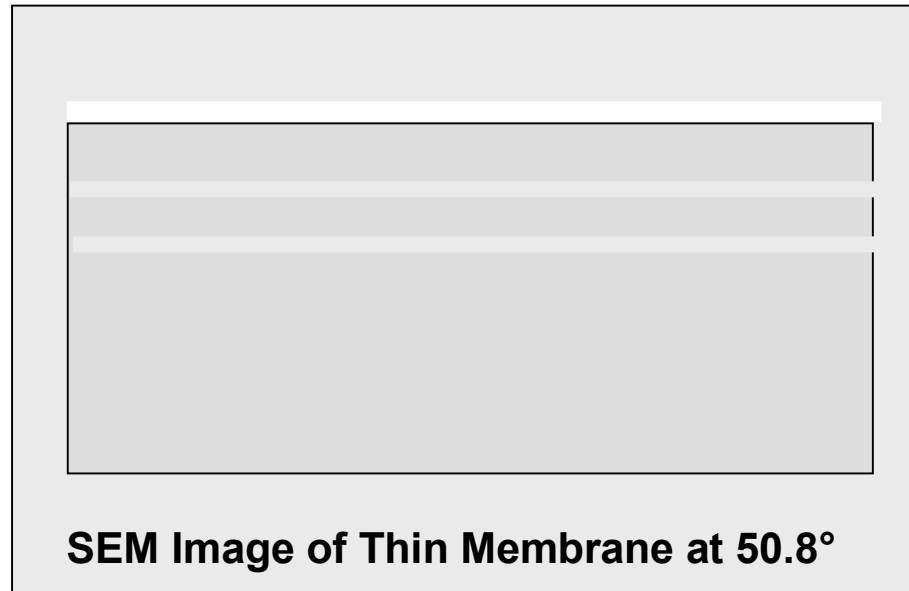
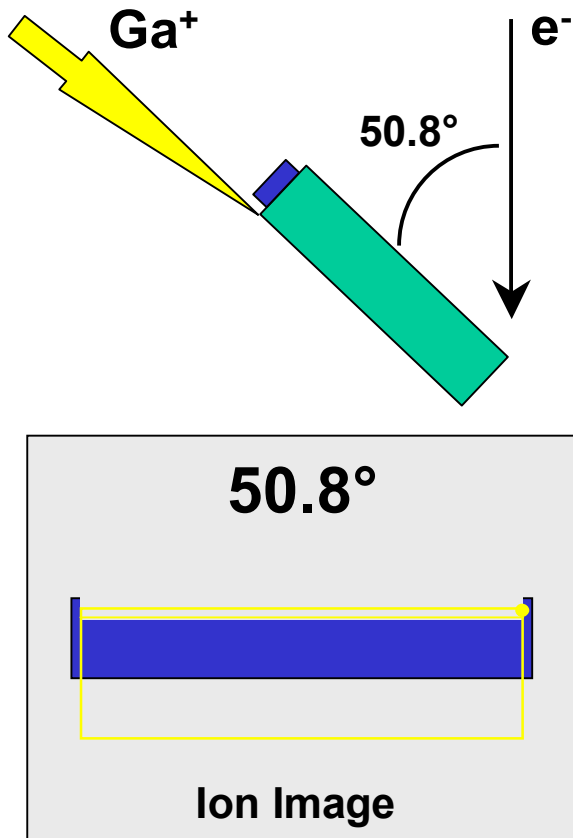


The interaction volume from the 5 keV beam is completely inside the sample volume and the SEM contrast of the membrane is normal. Set the contrast and brightness and do not change them.

Shown here, the ion image is not rotated and the Clean-up-cut box is rotated 180°.

(Alternatively, rotate the image, don't rotate the box and cut from the bottom of image on the screen.)

Endpoint Determination for TEM Samples in a Dual Beam Instrument



Extend the Clean-Up-Cut box beyond the bottom edge of the sample in order to more easily see the milled edges in the captured ion images.

The 5 keV beam is going through the thin sample and producing secondary electrons at the bottom of the sample. The brightness of the membrane is increased and the contrast decreases. Look for this and then when the ion beam starts to cut down the Pt protection —stop; the sample is thin.

S. D. Walck